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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

priority Application Serial No. .... 08/984,730  
priority Filing Date .... December 4, 1997  
Inventor ..... D.G. Custer et al.  
Assignee ..... Micron Technology, Inc.  
priority Group Art Unit ..... 3723  
priority Examiner ..... L. Wilson  
Attorney's Docket No. .... MI22-1172  
Title: Polishing Systems, Methods Of Polishing Substrates, and Methods Of Preparing  
Liquids For Semiconductor Fabrication Processes

PRELIMINARY AMENDMENT

To: Assistant Commissioner for Patents  
Washington, D.C. 20231

From: David G. Latwesen (Tel. 509-624-4276; Fax 509-838-3424)  
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AMENDMENTS

In the Specification

At p. 1, before the "Technical Field" section, insert

RELATED PATENT DATA

This patent resulted from a divisional application of U.S. Patent  
Application Serial No. 08/984,730, which was filed on December 4, 1997.

Amended Claims

Cancel claims 6-38.